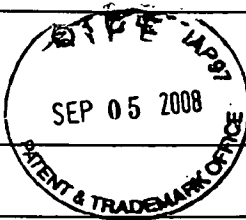


Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118039		APPLICATION NO. 10/733,454	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)							
APPLICANT(S) Shigemi OHTSU et al.							
FILING DATE December 12, 2003				GROUP 1791			

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Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Date: September 5, 2008

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /M.V./

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